

Electronic Patent Application Fee Transmittal

Application Number:	10650886				
Filing Date:	28-Aug-2003				
Title of Invention:	IN-SITU STRIP PROCESS FOR POLYSILICON ETCHING IN DEEP SUB-MICRON TECHNOLOGY				
First Named Inventor/Applicant Name:	Horng-Wen Chen				
Filer:	James Kesterson/Shelley Butz				
Attorney Docket Number:	TSM6283131RI				
Filed as Large Entity					
Utility Filing Fees					
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:					
Pages:					
Claims:					
Miscellaneous-Filing:					
Petition:					
Patent-Appeals-and-Interference:					
Post-Allowance-and-Post-Issuance:					
Utility Appl issue fee		1501	1	1400	1400
Publ. Fee- early, voluntary, or normal		1504	1	300	300

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension-of-Time:				
Miscellaneous:				
		Total in USD (\$)		1700